

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

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In re Application of:	)	
	)	
Han-Ming Wu et al.	)	Examiner: Nguyen, Hung
	)	
Serial No: 10/759,641	)	Art Unit: 2851
	)	
Filed: January 16, 2004	)	
	)	
For: Purging Gas from a	)	
Photolithography Enclosure	)	
Between a Mask Protective	)	
Device and a Pattern Mask	)	

PRELIMINARY AMENDMENT

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

Prior to examination of the present RCE application, the Applicants respectfully request that the Examiner enter the following amendments and consider the following remarks.

CERTIFICATE OF FACSIMILE

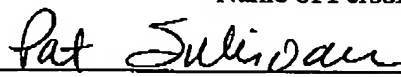
I hereby certify that this correspondence is being transmitted via facsimile on the date shown below to the United States Patent and Trademark Office.

March 6, 2006

Date of Deposit

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